

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu, et al.

Serial No: 09/546,174

Filed: April 11, 2000

For: High Density Plasma Chemical Vapor Deposition
Process

Art Unit: 1711

Confirmation No. 4793

Examiner: Sergent, Rabon A.

CERTIFICATE OF ELECTRONIC TRANSMISSION

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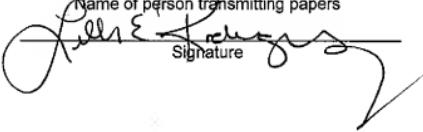
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